



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Thomas A. Figura, Kevin Donohoe, & Thomas Dunbar

Serial No.: 09/471,460

Filed: December 22, 1999

Title: USE OF A PLASMA SOURCE TO FORM A LAYER
DURING THE FORMATION OF A SEMICONDUCTOR DEVICE

§
§ Group Art Unit: 2825
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§ Application Examiner: Calvin Lee
§
§ Atty. Docket: 94-0280.03
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AMENDMENT AFTER THE CONTINUED PROSECUTION APPLICATION
AND RESPONSE TO THE OFFICE ACTION DATED JUNE 6, 2000

Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

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ADDRESSED TO THE ASSISTANT COMMISSIONER FOR
PATENTS, WASHINGTON, D.C. 20231

Frederick Thomas Dunbar
Signature

Applicants submit this Amendment and Response to the Office Action dated June 6, 2000. Please amend the accompanying continued prosecution application as follows.

IN THE SPECIFICATION

In the section labeled "RELATED APPLICATIONS" added in the Preliminary Amendment, please add at the end of that section the following:

-- This application contains subject matter related to U.S. application Ser. No. 09/470, 650, which is also a divisional of pending U.S. application Ser. No. 09/046,835 mentioned above.

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